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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO
10/708,059	02/06/2004	Long-Hui Lin	LKSP0032USA	2058
27765	7590 03/16/2005		EXAMINER	
NORTH AMERICA INTERNATIONAL PATENT OFFICE (NAIPC) P.O. BOX 506			RAO, SHEELA S	
	D, VA 22116		ART UNIT	PAPER NUMBER
			2125	

DATE MAILED: 03/16/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

	Application No.	Applicant(s)	
	10/708,059	LIN ET AL.	
Office Action Summary	Examiner	Art Unit	
	Sheela Rao	2125	
The MAILING DATE of this communication a eriod for Reply	appears on the cover sheet w	th the correspondence address	
A SHORTENED STATUTORY PERIOD FOR REF THE MAILING DATE OF THIS COMMUNICATION - Extensions of time may be available under the provisions of 37 CFR after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a r - If NO period for reply is specified above, the maximum statutory perion - Failure to reply within the set or extended period for reply will, by stat Any reply received by the Office later than three months after the ma earned patent term adjustment. See 37 CFR 1.704(b).	N. 1.136(a). In no event, however, may a reply within the statutory minimum of third od will apply and will expire SIX (6) MON tute, cause the application to become AE	reply be timely filed ty (30) days will be considered timely. ITHS from the mailing date of this communication BANDONED (35 U.S.C. § 133).	on.
1) Pagagaive to communication(s) filed on 06	Enhruany 2004		
1) Responsive to communication(s) filed on <u>06</u> 2a) This action is FINAL . 2b) ▼ This action is FINAL .	his action is non-final.		
3) Since this application is in condition for allow		ers prosecution as to the merits i	s
closed in accordance with the practice unde	•	· ·	J
·	, _,, panto quayto, 1000 010	,	
isposition of Claims A) Claim(a) 1.12 in/ore pending in the application	••		
4) Claim(s) 1-12 is/are pending in the application			
4a) Of the above claim(s) is/are withdoms 5) Claim(s) is/are allowed.	rawii iroin consideration.		
6) Claim(s) 1-12 is/are rejected.			
7) Claim(s) is/are objected to.			
8) Claim(s) are subject to restriction and	d/or election requirement.		
pplication Papers	·		
The specification is objected to by the Examination	iner		·
10) ☐ The drawing(s) filed on <u>06 February 2004</u> is/a		objected to by the Examiner	
Applicant may not request that any objection to the	•	· ·	
Replacement drawing sheet(s) including the corre	= * *	, ,	d).
11) The oath or declaration is objected to by the	•	· · · · · · · · · · · · · · · · · · ·	
riority under 35 U.S.C. § 119			
12) Acknowledgment is made of a claim for foreign	an priority under 35 U.S.C. 8	119(a)-(d) or (f).	
a) ☐ All b) ☐ Some * c) ☐ None of:	5 - processing annual de district 3	- 1-1 1-1 1.1.	
1. Certified copies of the priority docume	ents have been received.		
2. Certified copies of the priority docume		pplication No	
3. Copies of the certified copies of the pr	riority documents have been	received in this National Stage	
application from the International Bure	eau (PCT Rule 17.2(a)).		
* See the attached detailed Office action for a li	st of the certified copies not	received.	
tachment(s)	_		
Notice of References Cited (PTO-892) Notice of Draftsperson's Patent Drawing Review (PTO-948)		iummary (PTO-413) s)/Mail Date	
Information Disclosure Statement(s) (PTO-1449 or PTO/SB/0	 1	nformal Patent Application (PTO-152)	
Paper No(s)/Mail Date	6) Other:		

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DETAILED ACTION

1. Claims 1-12 are presented for examination and are pending.

Claim Rejections - 35 USC § 102

2. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 3. Claims 1-12 are rejected under 35 U.S.C. 102(b) as being anticipated by Steffan et al. in US Patent No. 6,512,842 B1.

The patented reference of prior art to Steffan et al. teaches of a method and apparatus for the analysis of defects in a semiconductor wafers. In doing so, a production lot of wafers are scanned and analyzed in an analysis tool, such as the SEM (scanning electron microscope), optical tools, or the FIB (fixed ion beam). The analyzed data is then stored in the defect management system, along with images of the wafers and assigned descriptors. Furthermore, a review station is present which assigns refined descriptive labels to the images and this data is saved in the database. In addition to the defect inspection process, the ADC (automatic defect classification) protocol is used for classifying the types of defects. As per the limitations of the instant claims, a manual inspection is also taught by the prior art of record. As stated in col. 4: II.50-59, an operator is able to review the images at the review station and compare those reviewed to other images in the database. Upon having reviewed the retrieved images, the operator can revise the descriptors to refine the database.

For the reasons stated above, the limitations of the instant invention as claimed by instant claims 1-12 is taught by the prior arts of record; thereby, rendering the instant claims unpatentable.

Conclusion

4. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure.

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Art Unit: 2125

Applicant is advised to carefully review the cited art, as evidence of the state of the art, in preparation for responding to this Office action.

O'Dell et al.

USPN 6,826,298 B1

teaches of an automated wafer defect inspection system

and process

Hsu et al.

USPN 6,643,006 B1

teaches a data management system for reviewing

semiconductor wafers

5. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Sheela Rao whose telephone number is (571) 272-3751. The examiner can normally be reached Monday - Friday from 9:00 am to 4:00 pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Leo Picard, can be reached on (571) 272-3749.

Any response to this action should be mailed to:

Commissioner of Patents and Trademarks Washington, D.C. 20231

or faxed to:

(703) 305-3718 for Official Communications

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the Group receptionist whose telephone number is (703) 305-3900.

L- P.P.

Sheela S. Rao March 14, 2005

> LEO PICARD SUPERVISORY PATENT EXAMINER TECHNOLOGY CENTER 2100